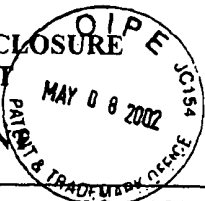


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STATEMENT

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Docket: 4641-61349

App: 09/997,646

Applicant: Okino et al.

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Art Unit: 2812

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| Init.*    | Number    | Date      | Name          | Class | Sub | Filed |
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## FOREIGN PATENT DOCUMENTS

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